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Serial No. 09/412,510

INFORMATION DISCLOSURE STATEMENT

Applicants: Kenji ITOH et al.

09/418/15/10

Filing Date: October 05, 1999

Group Art Unit: 1762

U.S. PATENT DOCUM

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date (if appropriate)
IN FO	4,328,258	05/04/1982	Coleman	1		
JPJV	4,438,188	03/20/1984	Shimatani et al.			<u> </u>
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epartment of Commerce Form PTO-1449 Atty Docket 0756-2 Serial No. 09/412,510 it and Trademark Office (Rev. 8-83) INFORMATION DISCLOSURE STATEMENT 09/412,510 Applicants: Kenji ITOH et al. SEP 1 8 2001 Filing Date: October 05, 1999 **Group Art Unit: 1762** (Including Author, Title, Date, Pertinent Pages, Etc.) Examiner Initial Zou et al., "The Deposition and Study of Hard Carbon Films", pp. 3914-3918/May 15, 1989, J. Appl. Phys. Vol. 65 David et al., "Plasma Deposition and Etching of Diamond-Like Carbon Films", pp. 367-376, March 1991, AIChE Journal Bubenzer et al., "RF-Plasma Deposited Amorphous Hydrogenated Hard Carbon Thin Films: Preparation, Properties, and Applications", pp. 4590-4595, August 1983, J. Appl. Phys. 54 (8) Angus et al., "Low-Pressure, Metastable Growth of Diamond and "Diamondlike" Phases", pp. 913-921 (August 19.) 1988, Science, Vol. 241 L...Holland, "Some Characteristics and Uses of Low Pressure Plasmas in Materials Science", pp. 5-15, Jan./Feb. 1977, J. Vac. Sci. Technol., Vol. 14, No. 1 Tsai et al., "Characterization of Diamondlike Carbon Films and Their Application as Overcoats on Thin-Film Media for Magnetic Recording", pp. 3287-3912, Nov./Dec. 1987, J. Vac. Sci. Technol. A 5 (6)

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